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Front Matter: Volume 11568

, "Front Matter: Volume 11568," Proc. SPIE 11568, AOPC 2020: Optics Ultra Precision Manufacturing and Testing, 1156801 (5 November 2020); doi: 10.1117/12.2585924

SPIE.

Event: Applied Optics and Photonics China (AOPC 2020), 2020, Beijing, China

PROCEEDINGS OF SPIE

AOPC 2020: Optics Ultra Precision Manufacturing and Testing

Lingbao Kong
Dawei Zhang
Xichun Luo
Editors

29 - 30 June 2020
Shanghai, China

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Chinese Society for Optical Engineering (CSOE) (China) • Shanghai Engineering Research Center of Ultra-Precision Optical Manufacturing, Fudan University (China) • Shanghai Engineering Research Center of Extreme Optical Manufacturing and Measurement (China)

Published by
SPIE

Volume 11568

Proceedings of SPIE 0277-786X, V. 11568

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

AOPC 2020: Optics Ultra Precision Manufacturing and Testing, edited by Lingbao Kong,
Dawei Zhang, Xichun Luo, Proc. of SPIE Vol. 11568, 1156801 · © 2020 SPIE
CCC code: 0277-786X/20/\$21 · doi: 10.1117/12.2585924

Proc. of SPIE Vol. 11568 1156801-1

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Author(s), "Title of Paper," in *AOPC 2020: Optics Ultra Precision Manufacturing and Testing*, edited by Lingbao Kong, Dawei Zhang, Xichun Luo, Proceedings of SPIE Vol. 11568 (SPIE, Bellingham, WA, 2020) Seven-digit Article CID Number.

ISSN: 0277-786X
ISSN: 1996-756X (electronic)

ISBN: 9781510639577
ISBN: 9781510639584 (electronic)

Published by
SPIE
P.O. Box 10, Bellingham, Washington 98227-0010 USA
Telephone +1 360 676 3290 (Pacific Time) · Fax +1 360 647 1445
SPIE.org
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